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Optimizing the Design of Polymer Based Unimorph Actuator using COMSOL Multiphysics

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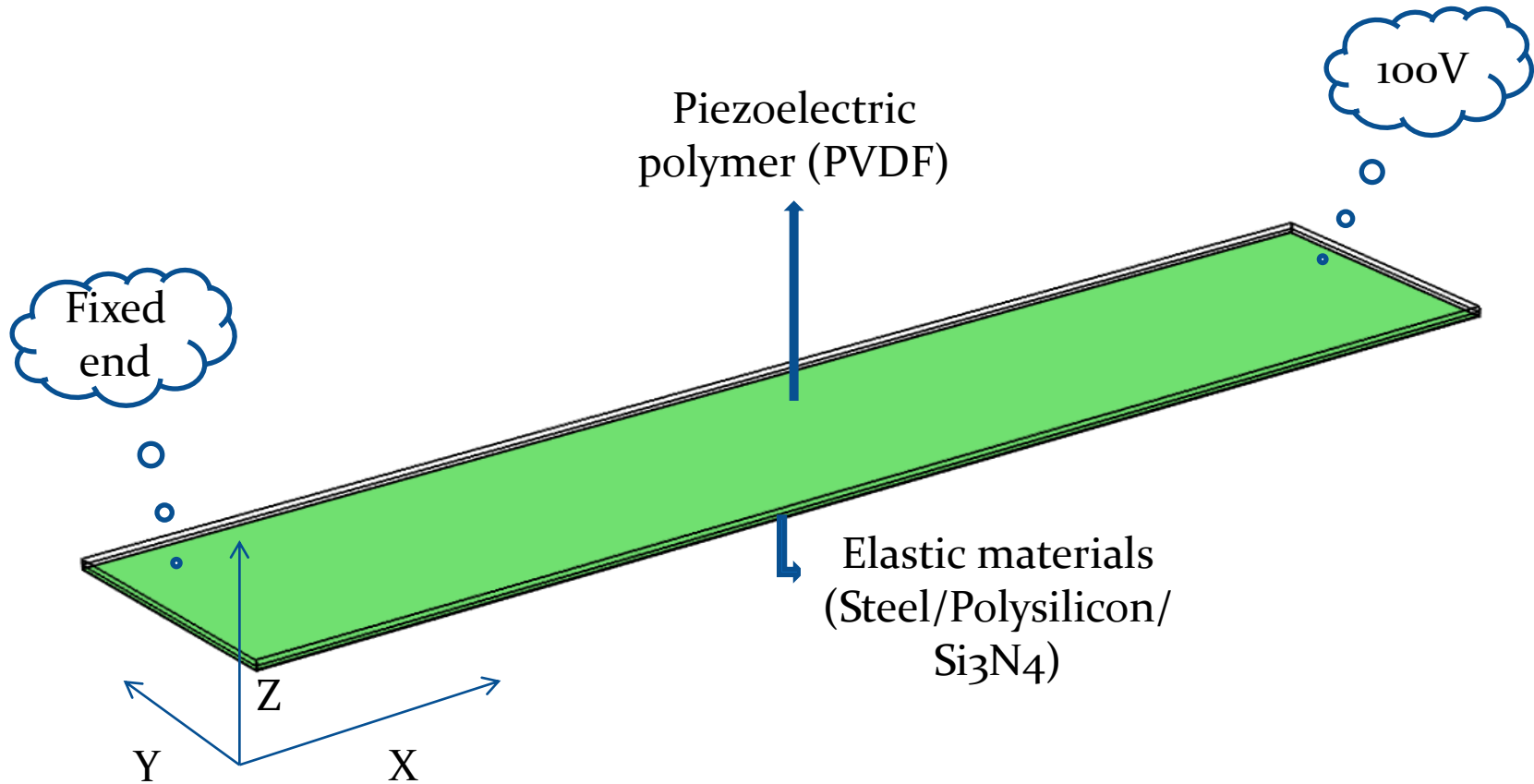
Outline

- Why polymer based unimorph actuator.
- Our unimorph actuator.
- Governing Equations.
- Tools used for simulation.
- Results and discussion.
- Conclusion.

Polymer Based Unimorph Actuator

- Compared to bimorph and multilayer structures, **simple structure** and **easy assembly**.
- **Aeronautical applications** - flexibility, durability and light weight material with high degree of robustness.
piezoelectric ceramics - **brittle** and heavier
Solution- piezoelectric polymers. **PVDF** is the most preferred polymer.
- **Tip deflection** depends on its **geometrical dimensions** and **material properties** etc. need to optimize the design parameters .

Piezoelectric Unimorph configuration taken.



Governing equations

- Converse piezoelectric effect:

$$\{S\} = [s^E] \{T\} + [d^t] \{E\}$$

Mechanical strain
vector

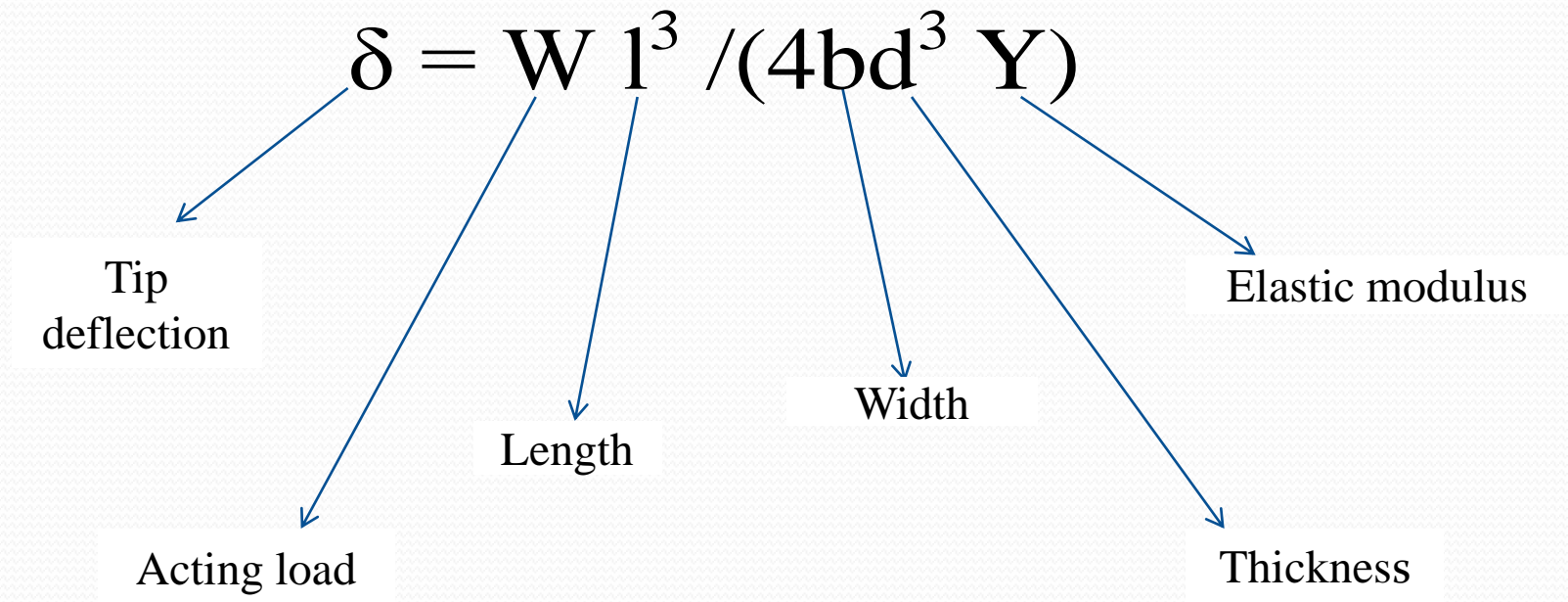
Mechanical stress
vector

Electric field
vector

elastic compliance
tensor at constant
electric field

Transverse piezoelectric
coefficient tensor

- Mechanical behaviour of rectangular beam made up of some elastic material say (Steel/ Polysilicon/ Si_3N_4):



Tools used for computation

- Comsol Multiphysics Version 4.2 .
- An analytical relation for the deflection of a piezoelectric Unimorph cantilever Beam:

$$\delta = \frac{3L^2}{2t} \cdot \frac{2AB(1+B)^2}{A^2B^4 + 2A(2B + 3B^2 + 2B^3) + 1} \cdot d_{31}E_3$$

Where A: Ratio of elastic modulus of elastic material over elastic modulus of piezoelectric material

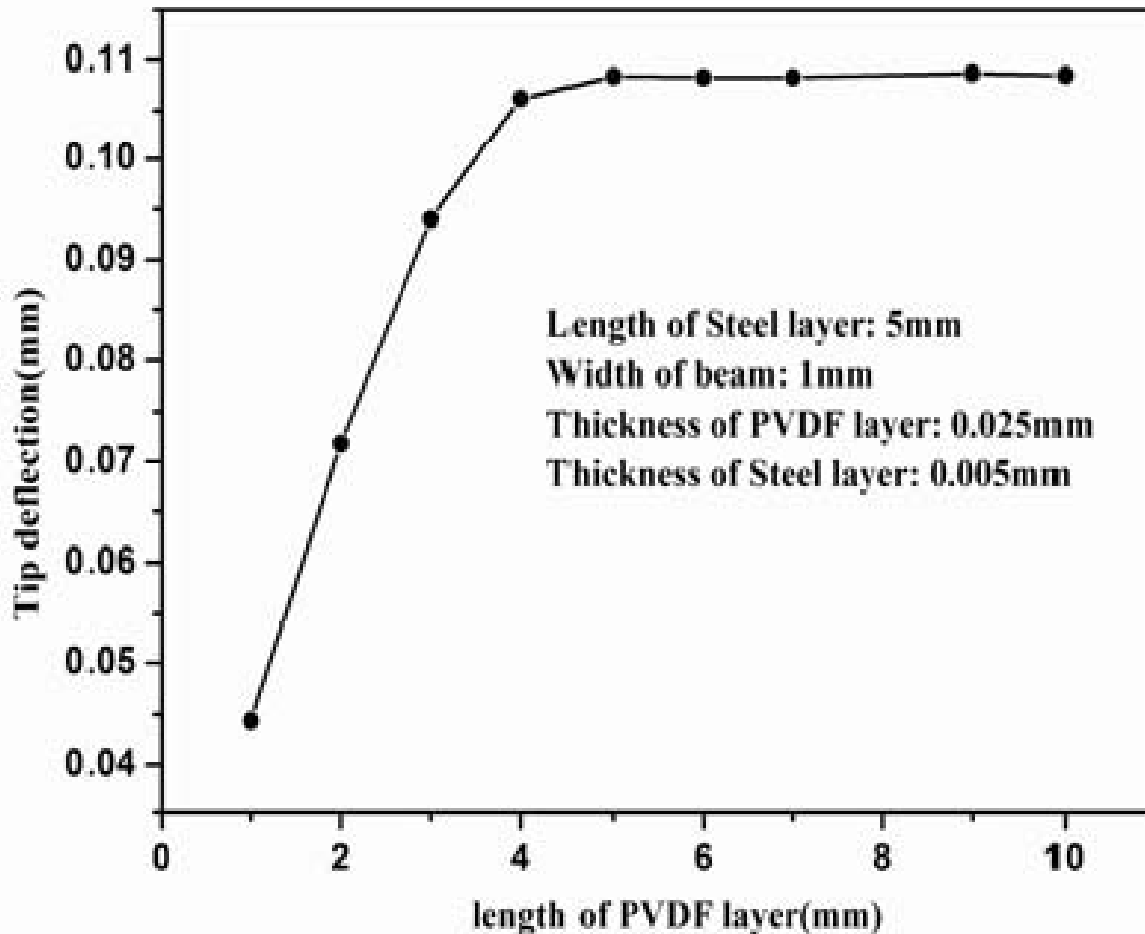
B: Ratio of thickness of elastic material over thickness of piezoelectric material.

L: Length of the cantilever beam.

d_{31} : Piezoelectric coupling coefficient.

E_3 : Applied electric field in 3rd direction

Variation in the tip deflection of the beam with the length of the PVDF layer



Increase:

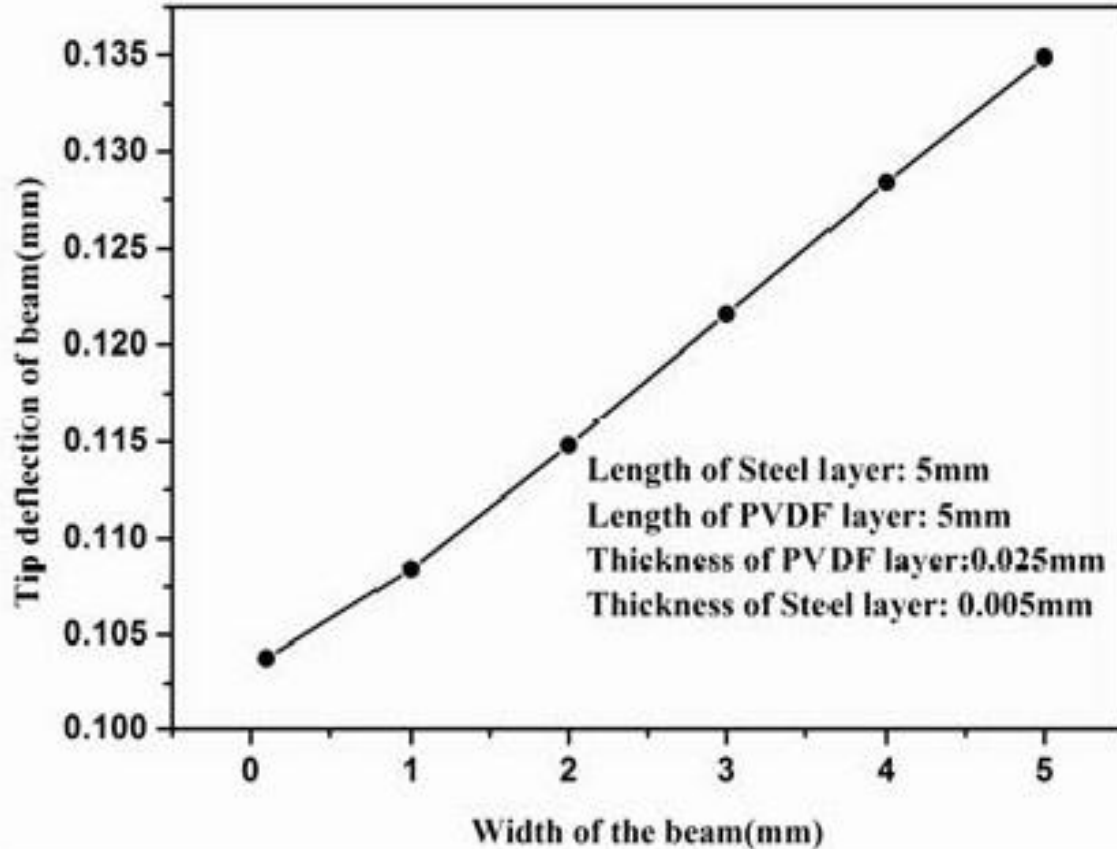
Load and length effect

Saturation:

Converse piezoelectric effect
=> strain along X direction.

Elastic behaviour of substrate
=> bending deformation along Z direction.

Variation in the tip deflection of the beam with the width of cantilever



Insignificant increase:

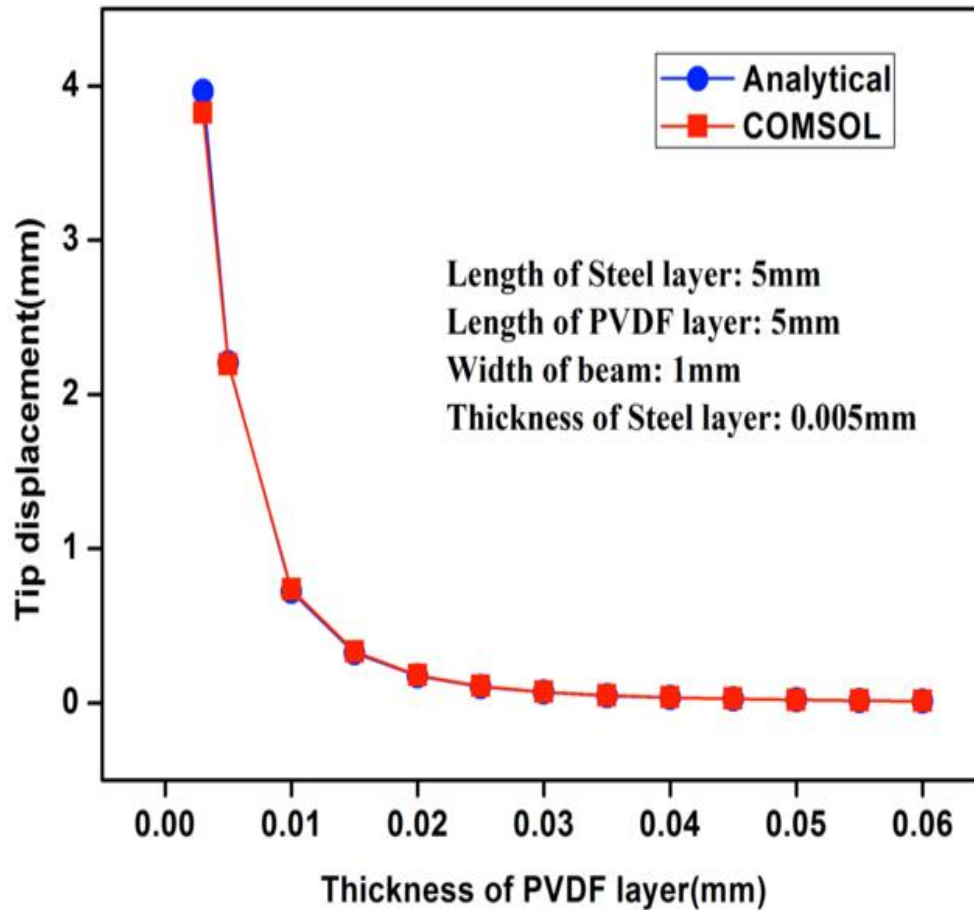
$$\text{-Tip deflection } \propto \frac{1}{I_{\text{rectangular}}}$$

$$I_{\text{rectangular}} \propto \text{width} \uparrow$$

$$\text{-Tip deflection } \propto \text{load}$$

$$\text{Load } \propto \text{width} \uparrow$$

Variation in the tip deflection of the beam with the thickness of PVDF layer



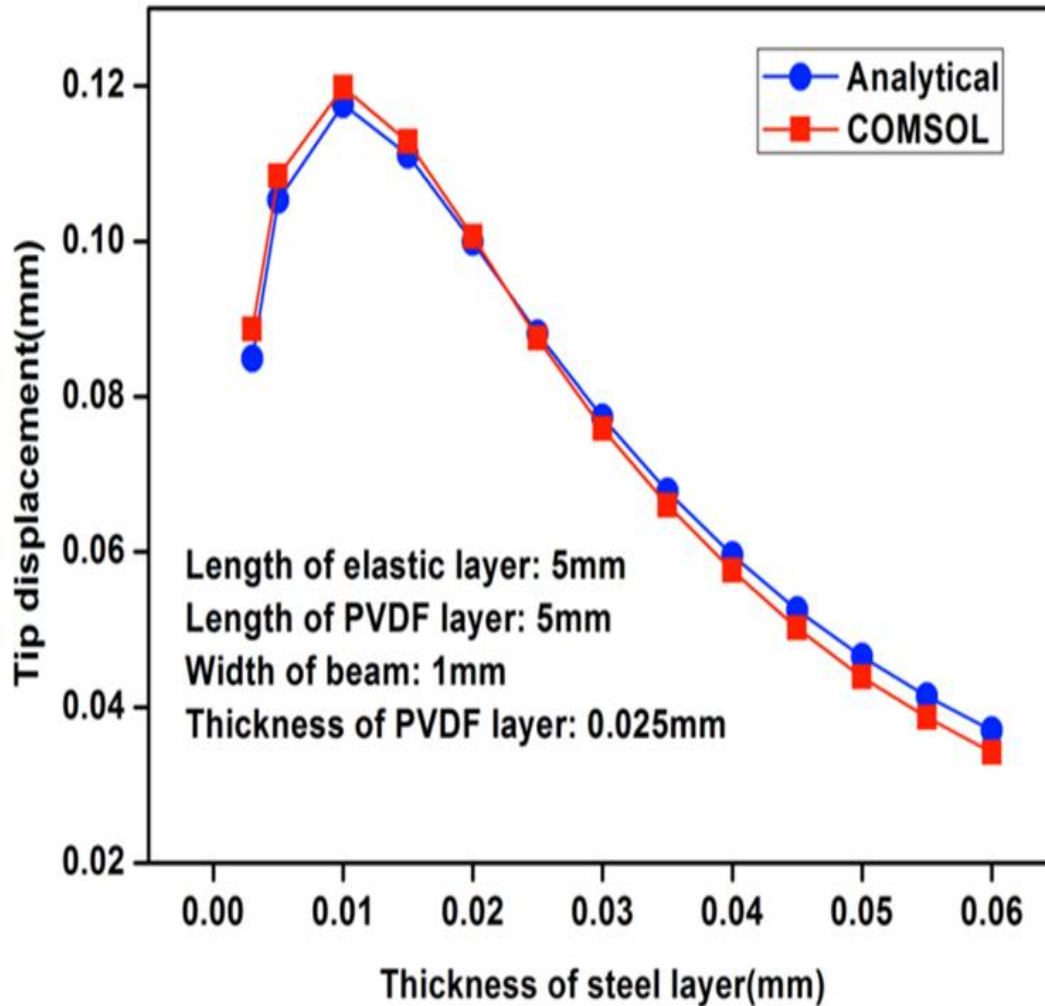
Increase:

- Strain \propto Electric field \propto thickness (↓)

- Tip deflection $\propto \frac{1}{I_{\text{rectangular}}}$

$I_{\text{rectangular}} \propto$ Thickness (↓)

Variation in the tip deflection of the beam with the thickness of steel layer



Increase:

-Tip deflection $\propto \frac{1}{I_{\text{rectangular}}}$

$I_{\text{rectangular}} \propto \text{Thickness} \downarrow$

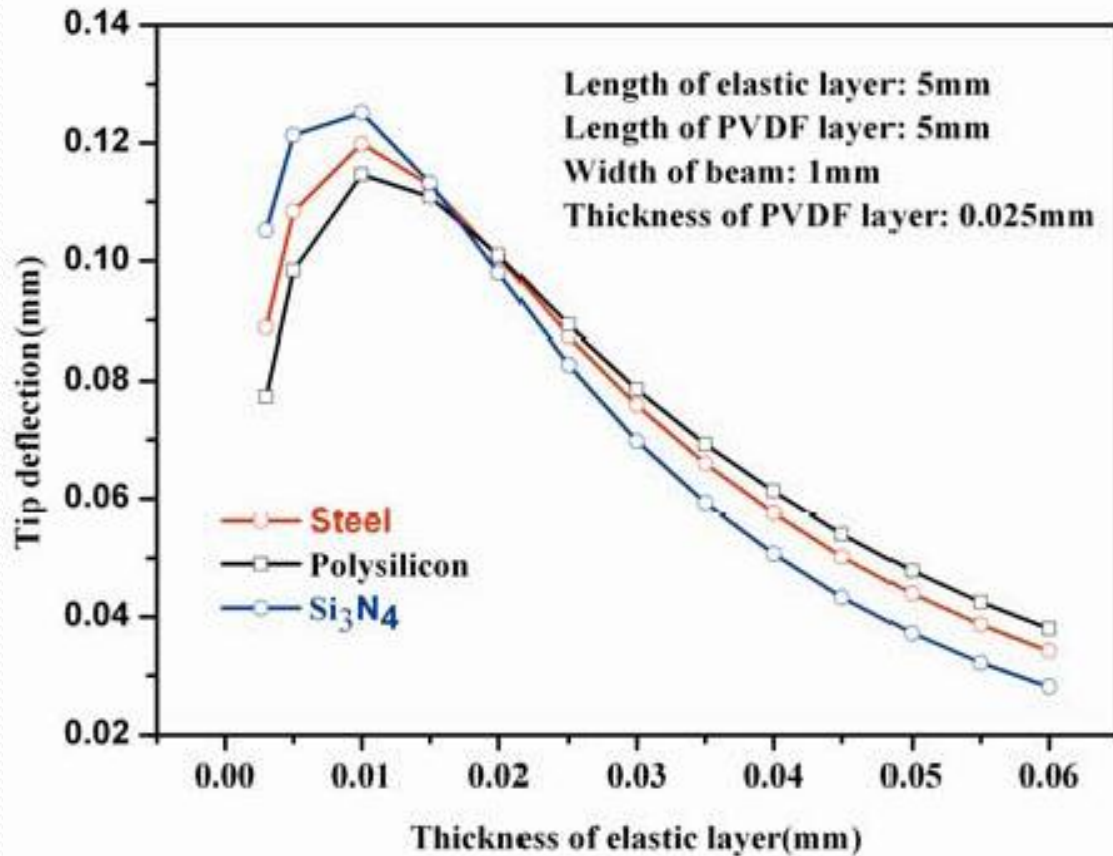
Decrease:

-Tip deflection $\propto \text{Load}$

$\text{Load} \propto \text{Thickness} \downarrow$

-Less bending in third direction due to thin elastic layer.

Variation in the tip deflection of the beam with thickness for three different materials



Anamoly:

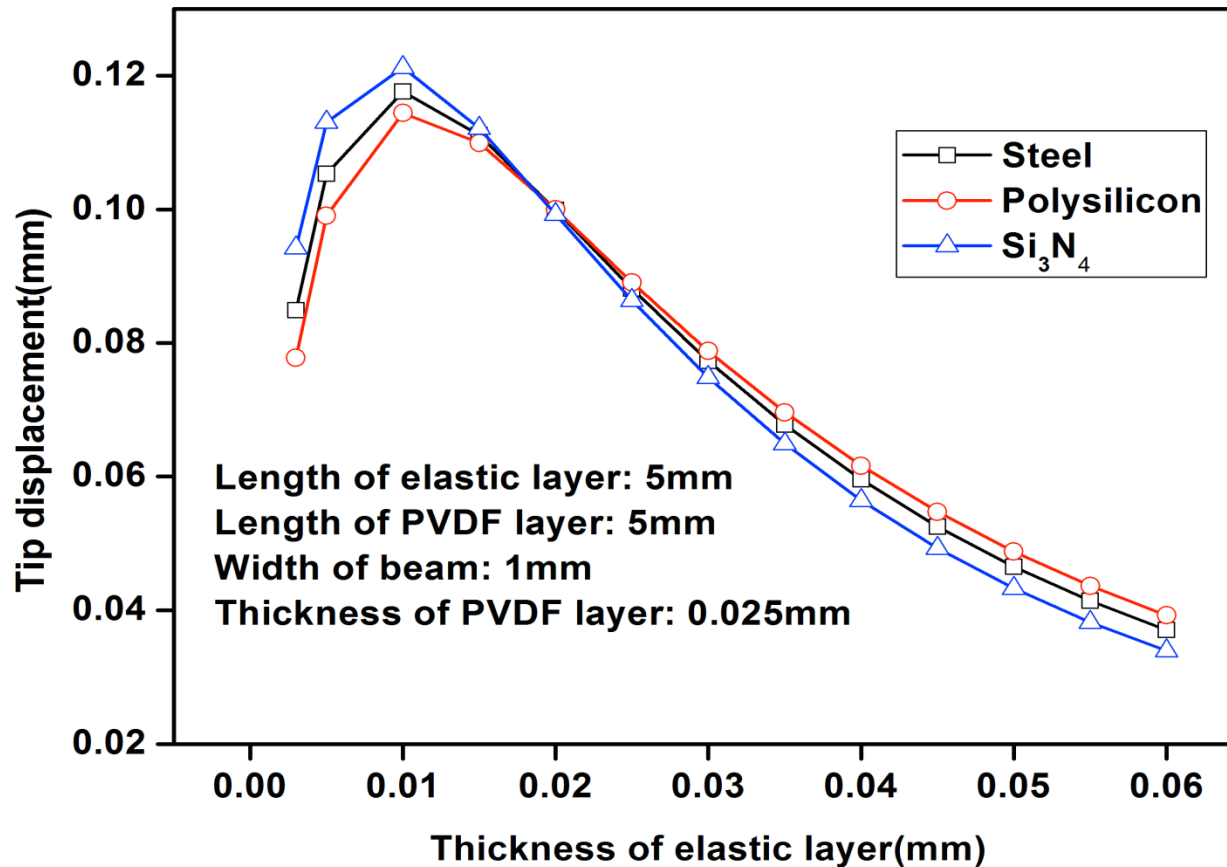
-Tip deflection \propto elastic modulus.

Elastic modulus:

Si₃N₄>Steel>Polysilicon.

-For thin elastic layer elastic modulus of piezoelectric layer (<elastic layer) is also going to decide the Unimorph bending.

Variation in the tip deflection of the unimorph cantilever beam with dimension for three different materials using some analytical relations.



Conclusions

- Length of the piezoelectric layer \geq length of nonpiezoelectric elastic layer.
- PVDF thickness **more effective design parameter** as compared to thickness of passive layer. The lesser the thickness of the piezoelectric layer, higher is the deflection.
- Tip displacement for **Si₃N₄ layer is maximum** as compared to polysilicon and stainless steel being chosen as passive layer.

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THANK YOU